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PATENT  
Customer No. 22,852  
Attorney Docket No. 04329.3238

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
)  
Gaku MINAMIHABA et al. ) Group Art Unit: 2818  
)  
Application No.: 10/771,060 ) Examiner: Goodwin, David J.  
)  
Filed: February 4, 2004 ) Confirmation No. 2231  
)  
For: POLISHING PAD AND METHOD )  
OF MANUFACTURING )  
SEMICONDUCTOR DEVICES )

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**RESPONSE TO RESTRICTION REQUIREMENT**

In the Restriction Requirement mailed September 15, 2005, with a period for response extending to October 17, 2005 (October 15<sup>th</sup> being a Saturday), the Examiner required restriction under 35 U.S.C. § 121 between Group I (claims 1-10) and Group II (claims 11-20). Applicants elect to prosecute Group II, claims 11-20, characterized by the Examiner as drawn to a method of making a semiconductor device, without traverse.

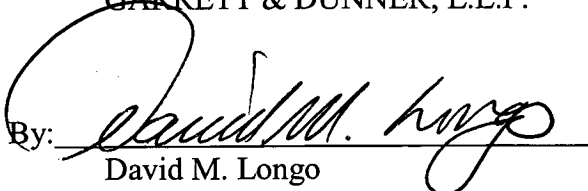
Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: October 17, 2005

By:

  
David M. Longo  
Reg. No. 53,235